

| Government eProcurement System | | Government eProcurement System | |
|--|---|--|---|
| | | Tender Details | |
| | | Date : 27-Jun-2022 12:35 PM | |
| | | Print | |
| Basic Details | | | |
| Organisation Chain | Council of Scientific and Industrial Research CSIO-Chandigarh - CSIR Purchase-CSIO - CSIR | | |
| Tender Reference Number | CSIO/3(5)2021-Pur | | |
| Tender ID | 2022_CSIR_120370_1 | | |
| Tender Type | Open Tender | Form of contract | EOI |
| Tender Category | Goods | No. of Covers | 1 |
| General Technical Evaluation Allowed | No | ItemWise Technical Evaluation Allowed | No |
| Payment Mode | Not Applicable | Is Multi Currency Allowed For BOQ | No |
| Is Multi Currency Allowed For Fee | No | Allow Two Stage Bidding | No |
| Cover Details, No. Of Covers - 1 | | | |
| Cover No | Cover | Document Type | Description |
| 1 | Fee/PreQual/Technical/Finance | .pdf | Expression of Interest for procurement of Nanoimprint Lithography System details attached |
| | | .xls | Link for online meeting |
| Tender Fee Details, [Total Fee in ₹ * - 0.00] | | EMD Fee Details | |
| Tender Fee in ₹ | 0.00 | EMD Amount in ₹ | 0.00 |
| Fee Payable To | Nil | EMD through BG/ST or EMD Exemption Allowed | No |
| Tender Fee Exemption Allowed | No | EMD Fee Type | fixed |
| | | EMD Percentage | NA |
| | | EMD Payable To | Nil |
| | | EMD Payable At | Nil |
| Click to view modification history | | | |
| Work /Item(s) | | | |
| Title | CSIO/3(5)2021-Pur | | |
| Work Description | Expression of Interest for procurement of Nanoimprint Lithography System details attached | | |
| Pre Qualification Details | Please refer Tender documents. | | |
| Independent External Monitor/Remarks | NA | | |
| Show Tender Value in Public Domain | No | | |
| Tender Value in ₹ | 0.00 | Product Category | Laboratory and scientific equipment |
| Contract Type | Tender | Sub category | NA |
| | | Bid Validity(Days) | 90 |
| | | Period Of Work (Days) | 45 |
| Location | CSIR-CSIO Sector 30 Chandigarh | Pincode | 160030 |
| | | Pre Bid Meeting Place | Online |
| Pre Bid Meeting Address | link of meeting attached in BOQ | Pre Bid Meeting Date | 13-Jul-2022 02:00 PM |
| | | Bid Opening Place | CSIR-CSIO |
| Should Allow NDA Tender | No | Allow Preferential Bidder | No |

| Critical Dates | | | |
|--|----------------------|--|----------------------|
| Publish Date | 27-Jun-2022 01:00 PM | Bid Opening Date | 15-Jul-2022 03:30 PM |
| Document Download / Sale Start Date | 27-Jun-2022 01:00 PM | Document Download / Sale End Date | 14-Jul-2022 03:00 PM |
| Clarification Start Date | 27-Jun-2022 01:00 PM | Clarification End Date | 11-Jul-2022 03:00 PM |
| Bid Submission Start Date | 27-Jun-2022 01:00 PM | Bid Submission End Date | 14-Jul-2022 03:00 PM |

| Tender Documents | | | | |
|----------------------------|-------------|----------------------|---|--|
| NIT Document | S.No | Document Name | Description | Document Size (in KB) |
| | 1 | Tendernotice_1.pdf | Expression of Interest for procurement of Nanoimprint Lithography System details attached | 213.09 |
| Work Item Documents | S.No | Document Type | Document Name | Description |
| | 1 | BOQ | BOQ_131262.xls | Expression of Interest for procurement of Nanoimprint Lithography System |

| Auto Extension Corrigendum Properties for Tender | | |
|---|--|--|
| Iteration | No. of bids required for bid opening a tender | Tender gets extended to No. of days |
| 1. | 2 | 7 |

| Bid Openers List | | | |
|-------------------------|-----------------------------|------------------------|-------------------------|
| S.No | Bid Opener Login Id | Bid Opener Name | Certificate Name |
| 1. | ramesh.eproc@csir.res.in | Ramesh Kumar | RAMESH KUMAR |
| 2. | sunder.eproc@csir.res.in | Sunder Lal | SUNDER LAL |
| 3. | jayantrao.eproc@csir.res.in | Jayant Mohan Rao | JAYANT MOHAN RAO |
| 4. | anilyadav.eproc@csir.res.in | Anil Kumar Yadav | ANIL KUMAR YADAV |

| GeMARPTS Details | |
|---|------------------------------|
| Reason for non availability of GeMARPTS ID | Urgent nature of Procurement |
| Remarks | Expression of Interest |
| Document Name | NanoimprintTPC.pdf |
| Document Size (in KB) | 374.96 |

| Tender Properties | | | |
|--|--------|---|-----|
| Auto Tendering Process allowed | No | Show Technical bid status | Yes |
| Show Finance bid status | Yes | Show Bids Details | Yes |
| BoQ Comparative Chart model | Normal | BoQ Compative chart decimal places | 2 |
| BoQ Comparative Chart Rank Type | L | Form Based BoQ | No |

| Tender Inviting Authority | |
|----------------------------------|---|
| Name | Controller ofStores and Purchase |
| Address | The Director CSIR-CSIO Sector 30 Chandigarh 160 030 |

| Tender Creator Details | |
|-------------------------------|--|
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|---------------------|----------------------|
| Created By | Ramesh Kumar |
| Designation | Assistant |
| Created Date | 27-Jun-2022 12:08 PM |

Expression of Interest (EoI) for procurement of Nanoimprint Lithography System

Documents to be submitted by the OEM or Authorized Representative of OEM:

1. Model number(s) of the instrument which meets the specifications (or very closely matches the specifications).
2. Brochures/Catalogues w.r.t point no.1.
3. Compliance sheet of the specifications mentioned in the EoI. The compliance sheet must be vetted by the OEM. If any of the specification is not complying, then mention the actual parameter value for the instrument Model mentioned in point no. 1.
4. Valid authorization letter from OEM.
5. Domestic user list of similar system with Model No.
6. Any other relevant point the OEM/ Authorized Representative of OEM wants to share or discuss.

Nanoimprint Lithography System Specifications

| | | |
|-----------------------------------|--|--|
| A. Substrate and Stamp | | |
| 1. | Substrate Size | 8-inch diameter or larger; System should be able to handle substrates of smaller sizes of diameter 2", 3", 4", 6". Suitable substrate adapters and vacuum chucks should be provided. |
| 2. | Substrate Thickness | (0.1mm) to (10mm or higher) |
| 3. | Substrate material | System should support imprinting on following materials: Polymethylmethacrylate (PMMA), polycarbonate (PC), Fused Silica, Quartz, Optical Glasses (BK7 etc.), Silicon Wafers, Metals, Ge, ZnSe, Sapphire, GaAs |
| 4. | Imprint materials | System should support following materials for imprinting: polymethylmethacrylate (PMMA), UV polymerizable resists, Thermoplastic polymers resists, Cyclo-olefin copolymer (COC), Cycloolefin polymer (COP), Carbor-based Polycarbonate (CPC), Sol-gel based materials, Optical glasses (Silica gel-based) |
| 5. | Stamp Size | 8-inch diameter or larger System should be able to handle stamps of smaller sizes of diameter 2", 3", 4", 6". Suitable vacuum chucks, holders for stamp should be provided. |
| 6. | Stamp thickness | (0.1mm) to (5mm or higher) |
| 7. | Stamp material | System should support following stamp materials: Silicon, quartz, nickel, polymethylmethacrylate (PMMA), polydimethylsiloxane (PDMS), cycloolefin copolymer (COC) and cycloolefin polymer (COP) |
| 8. | Maximum imprinting area | System should be able to perform imprinting on area from 0.5" inch diameter to 8" inch diameter |
| B. Imprinting requirements | | |
| 9. | Imprinting forms supported | Thermal, UV, Hot embossing |
| 10. | Resolution/feature size | The system should support fabrication of a wide range of feature sizes varying from: (30 nm or less) to (10 micrometer or higher) |
| 11. | Type of loading & unloading of substrate and stamp | Manual |
| 12. | Nano Imprinting process control | The process control in between the loading and unloading of the sample should be fully automated |
| 13. | Nano imprinting operation | The system should support operation in following mediums: Air, inert gas and vacuum |
| 14. | Step and Scan Imprinting | The system should have provision to perform step and scan imprint operation of small size stamp over 8-inch diameter. |
| C. Imprint parameters | | |
| 15. | Imprint pressure range | 0 - 30 bar (or higher) |

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| 16. | Vacuum requirement | The system should support operation on vacuum of 1.5 mbar or less |
| 17. | Temperature range for thermal imprinting | The system should support operating temperature ranging from: From ambient to 250° C with +/- 2 °C accuracy |
| 18. | Heating Rate for thermal imprinting | Programmable temperature ramp from 0.5 degrees to 3.3 °C/Sec |
| 19. | Cooling Rate for thermal imprinting | Cooling ramp rate of at least 50 degree /min |
| D. UV Source Specifications | | |
| 20. | UV Source wavelength | Tunable Source with at least 365 nm, 395 nm and 405 nm wavelengths; |
| 21. | UV Source Power | The average UV intensity should be 20 mW/cm ² or higher. UV Intensity tunable over wide range |
| 22. | UV Source Life | 10,000 hours or higher |
| E. Vacuum Pump | | |
| 23. | Class 100 cleanroom compatible dry vacuum pump for substrate and stamp holding compatible with the quoted model. | |
| F. Process Technology requirements | | |
| 24. | Process Technology for master stamp replication (soft mold compatible) | System should allow the master stamp to be replicated into a soft and flexible polymer material, which is then used as a stamp when imprinting on the target substrate |
| G. Computer controlled user interface | | |
| 25. | Computer controlled user interface | A workstation (Dell or HP or equivalent) compatible with the nanolithography equipment and loaded with genuine Windows 64-Bit operating system and pre-installed software for operating the equipment. Please quote for a perpetual license or extended support for the software. |
| 26. | Display | Complete logs of all the process and system parameters to be available and stored for future trouble shooting; Display tool for process parameters; Provision to alert the user in case of emergencies; Software for control and analysis of the imprint process, log files and equipment diagnostics needs to be supported for the lifetime of the tool |
| 27. | Program features | Programmable temperature, Programmable pressure selection Programmable time settings Programmable UV Power selection |
| 28. | Minimum number of process steps | The system should provide flexibility in operation to include a minimum of 20 process steps into a program to set the combinations of temperature, pressure, time, UV power or any other process parameter |
| H. Consumables & accessories | | |
| 29. | UV and Thermal imprint materials | To be provided with the instrument/system so as to demonstrate the functionality (especially resolution) of the system. These consumables will be retained by the institute. |

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| 30. | Stamp Consumables | At least 2 pieces of 8-inch diameter Quartz disks for stamp. Soft and flexible polymer material for fabricating soft stamp |
| 31. | Other accessories | All necessary tubing for connecting the system should in included. |

Acceptance Criteria:

General:

- Support of spares for minimum ten years.
- System should be clean room (Class 100) compatible.
- Manufacturer should have their service support/ office in India.
- There must be a provision for the remote control of the system for trouble shooting purposes.
- Should provide and quote all the necessary attachments for the system to be fully functional.
- All the technical specifications must be available for inspection in brochures/ catalogues/ application notes/ datasheets/ websites of Principal Manufacturer/OEM.

Warranty and service support:

- 12 months standard warranty from the date of installation/commissioning and final acceptance
- Vender/OEM should quote 02 yrs extended warranty + 02 yrs AMC for the system and sub-systems after the completion of standard warranty.
- The complete supply must be guaranteed for free repair / replacement and free software upgrades (wherever applicable) during the warranty period

Installation and commissioning:

- The supplier or the representative will do the installation and commissioning of the Nano imprint lithography unit as per above description at customer site and demonstrate the operation.
- After the successful installation, Supplier should provide complete free user training to at least 03 people.
- Training includes: Loading of substrate, alignment, setting up all parameters, unloading and recipe selection as per the workpiece and stamp material.
- Supplier will have to demonstrate the feature size; parameter ranges (temperature, pressure, UV light power) at customer site.
- At least one hard stamp and one soft test stamp with anti-sticking coating to demonstrate (i) UV-Nano imprint lithography, (ii) thermal nanoimprint lithography (iii) hot embossing. The stamp to demonstrate nanoimprint lithography must have a minimum feature size of 30 nm or less.
- Uniformity of imprinting over the 8" diameter with variation not more than +/- 5% should be demonstrated.
- Parameters setting, alignment and calibration using standard and nonstandard sample should be demonstrated during training.
- At least one standard recipe for each of the following should be pre-installed: (i) thermal nanoimprinting of a Polycarbonate (PC) using PDMS stamp, (ii) thermal nanoimprint on a resist, (iii) UV nanoimprint with a photoresist for use with hard stamps, (iv) UV nanoimprint with a photoresist for use with PDMS stamps (v) hot embossing.
- Users should be trained for operation, maintenance and servicing of the unit at customer site.
- Samples should be given as test samples for exposure during technical evaluation.
- Supplier should provide at least 10 samples for practice.
- Infrastructure/ utilities required for the installation should be intimated with the offer.

Documentation:

- All the documents and software for the system to be supplied in English language. A complete set of original manuals (soft and hard copies) including user manuals, maintenance manuals, troubleshooting tips, built assembly drawings, foundation layouts and manuals of all imported/purchased components, together with manuals of the system must be provided in English Language.

OEM/Supplier Criterion:

- Only reputed OEM/suppliers will be considered.
- At least one Nanoimprint Lithography System of the OEM should be installed in India for proven capability.
- A user list with the similar systems to be provided.
- Details /contact numbers, e-mail etc. of the place where the systems have been supplied and installed should be mentioned.